Contact Architectures for Tunnel Junction Devices
Tech ID: 27385 / UC Case 2017-132-0

BACKGROUND

A commonly explored limitation of p-GaN is that it is a poor current spreading layer and that traditional p-contacts will increase operating voltages in III-nitride devices. The introduction of tunnel junctions solves these issues and expands the opportunities for new device designs. This technology seizes the opportunity to improve the light extraction of flip chip LEDs.

DESCRIPTION

Researchers at the University of California, Santa Barbara have optimized light extraction of tunnel junction devices by increasing the reflectivity of the device’s mirror. The high reflectivity of silver has made it the first choice for previous mirror iterations, but its poor conductivity at the requisite thinness requires adjustments which then erode the benefits of its high reflectivity. This technology reconstructs the mirror, replacing silver with aluminum and coating the reflector with a dielectric high-reflection coating. This novel mirror architecture demonstrates a higher reflectivity than pure silver which leads to improved light extraction.

ADVANTAGES

▶ Improved light extraction
▶ Increased Chip power
▶ Current spreading with GaN
▶ No requirement for a TCO or silver mirrors
▶ Low contact resistivity & high reflectivity

APPLICATIONS

▶ LEDs
▶ III-Nitride devices
▶ Tunnel junctions

PATENT STATUS

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<tr>
<th>Country</th>
<th>Type</th>
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<td>United States Of America</td>
<td>Issued Patent</td>
<td>11,348,908</td>
<td>05/31/2022</td>
<td>2017-132</td>
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RELATED TECHNOLOGIES

▶ III-Nitride Tunnel Junction LED with High Wall Plug Efficiency
▶ Methods for Fabricating III-Nitride Tunnel Junction Devices
▶ Enhanced Light Extraction LED with a Tunnel Junction Contact Wafer Bonded to a Conductive Oxide

ADDITIONAL TECHNOLOGIES BY THESE INVENTORS

▶ Etching Technique for the Fabrication of Thin (Al, In, Ga)N Layers
▶ Lateral Growth Method for Defect Reduction of Semipolar Nitride Films
▶ Vertical Cavity Surface-Emitting Lasers with Continuous Wave Operation
▶ Eliminating Misfit Dislocations with In-Situ Compliant Substrate Formation
▶ III-Nitride-Based Vertical Cavity Surface Emitting Laser (VCSEL) with a Dielectric P-Side Lens
▶ Aluminum-cladding-free Nonpolar III-Nitride LEDs and LDs
▶ Low-Cost Zinc Oxide for High-Power-Output, GaN-Based LEDs (UC Case 2010-183)
▶ Defect Reduction in GaN films using in-situ SiNx Nanomask
▶ Enhanced Light Extraction LED with a Tunnel Junction Contact Wafer Bonded to a Conductive Oxide
▶ Implantable Light Irradiation Device For Photodynamic Therapy
▶ Low Temperature Deposition of Magnesium Doped Nitride Films
▶ Transparent Mirrorless (TML) LEDs
▶ Improved GaN Substrates Prepared with Ammonothermal Growth
▶ Optimization of Laser Bar Orientation for Nonpolar Laser Diodes
▶ Method for Enhancing Growth of Semipolar Nitride Devices
▶ Ultraviolet Laser Diode on Nano-Porous AlGaN template
▶ Improved Reliability & Enhanced Performance of III-Nitride Tunnel Junction Optoelectronic Devices
▶ Growth of Polyhedron-Shaped Gallium Nitride Bulk Crystals
▶ Nonpolar III-Nitride LEDs With Long Wavelength Emission
▶ Improved Fabrication of Nonpolar InGaN Thin Films, Heterostructures, and Devices
▶ Growth of High-Quality, Thick, Non-Polar M-Plane GaN Films
▶ High-Efficiency, Mirrorless Non-Polar and Semi-Polar Light Emitting Devices
▶ Method for Growing High-Quality Group III-Nitride Crystals
▶ Controlled Photoelectrochemical (PEC) Etching by Modification of Local Electrochemical Potential of Semiconductor Structure
▶ Oxyfluoride Phosphors for Use in White Light LEDs
▶ Technique for the Nitride Growth of Semipolar Thin Films, Heterostructures, and Semiconductor Devices
▶ (In,Ga,AI)N Optoelectronic Devices with Thicker Active Layers for Improved Performance
▶ Group III-N Light Emitting Devices Enhanced By Stress From Post-Growth Deposited Films
▶ Thermally Stable, Laser-Driven White Lighting Device
▶ MOCVD Growth of Planar Non-Polar M-Plane Gallium Nitride
▶ Methods for Fabricating III-Nitride Tunnel Junction Devices
▶ Low-Droop LED Structure on GaN Semi-polar Substrates
▶ Semi-polar LED/LD Devices on Relaxed Template with Misfit Dislocation at Hetero-interface
▶ Semipolar-Based Yellow, Green, Blue LEDs with Improved Performance
▶ III-Nitride-Based Devices Grown On Thin Template On Thermally Decomposed Material
▶ Growth of Semipolar III-V Nitride Films with Lower Defect Density
▶ III-Nitride Tunnel Junction LED with High Wall Plug Efficiency
▶ Tunable White Light Based on Polarization-Sensitive LEDs
▶ Cleaved Facet Edge-Emitting Laser Diodes Grown on Semipolar GaN
▶ Growth of High-Performance M-plane GaN Optical Devices
▶ Packaging Technique for the Fabrication of Polarized Light Emitting Diodes
Improved Anisotropic Strain Control in Semipolar Nitride Devices

Novel Multilayer Structure for High-Efficiency UV and Far-UV Light-Emitting Devices

III-V Nitride Device Structures on Patterned Substrates

Method for Increasing GaN Substrate Area in Nitride Devices

High-Intensity Solid State White Laser Diode

Nitride Based Ultraviolet LED with an Ultraviolet Transparent Contact

GaN-Based Thermoelectric Device for Micro-Power Generation

Limiting Strain-Relaxation in III-Nitride Heterostructures by Substrate Patterning

LED Device Structures with Minimized Light Re-Absorption

Growth of Planar Semi-Polar Gallium Nitride

High-Efficiency and High-Power III-Nitride Devices Grown on or Above a Strain Relaxed Template

UV Optoelectronic Devices Based on Nonpolar and Semi-polar AlInN and AlInGaN Alloys

Defect Reduction of Non-Polar and Semi-Polar III-Nitrides

III-Nitride Based VCSEL with Curved Mirror on P-Side of the Aperture

Enhancing Growth of Semipolar (Al,In,Ga,B)N Films via MOCVD

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